

Spectromicroscopy at the XM-1

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ABSTRACT

The XM-1 x-ray microscope was built to obtain high-resolution transmission images from a wide variety of thick (< 10 micron) samples. Modeled after a conventional full-field microscope, XM-1 makes use of zone plates for the condenser and objective elements. Recent work has enabled the microscope to be used for spectroscopic imaging as well. The bandwidth of light on the sample is limited by a linear monochromator which is formed by the combination of a condenser zone plate (CZP) and a pinhole at the sample plane. This combination gives a good spectral resolution which has been measured to be $\lambda/\Delta\lambda = 700$. This is high enough to be able to distinguish between different elements and even some chemical states on the same scale as the spatial resolution of the instrument which is 36 nm. The measured spectral resolution and the calculated spectral resolution will both be shown.

INTRODUCTION

The XM-1 x-ray microscope is a full field imaging microscope (1). Radiation produced by a bending magnet at the Advanced Light Source (ALS) is collected by a “large” (9 mm diameter) fresnel condenser zone plate (CZP) which projects the light through a pinhole and illuminates the sample. The photon energy which illuminates the sample can be changed within 250 and 900 eV. The light that passes through the sample is imaged through a high precision objective micro zone plate (MZIP) (45 μm diameter) and magnified onto a CCD camera. The field of view of the microscope is 10 μm with a spatial resolution of 36 nm.

The monochromator is composed of the CZP and a pinhole about 100 μm from the sample plane and is used to control the sample illumination wavelength. Zone plates have chromatic aberrations, so a change in the distance between the CZP and the sample changes the energy which is focused onto the sample plane. In order to uniformly illuminate the object, the CZP is uniformly scanned to fill the area being imaged. Since the spectral resolution is highest at the center of the spot from the CZP, reducing the area of the CZP scanning motion increases the spectral resolution with a corresponding decrease in the field of view. The pinhole is at a location very near to the sample plane compared to the CZP to sample plane distance (200 mm), so the aperture of the monochromator system is often limited by the size of the sample plane being imaged. The main function of the pinhole is to reduce background light in the system, thus improving spectral purity. During spectroscopic imaging with XM-1, the MZIP and CCD camera also move in order to form a proper image at each energy.

In order to obtain a spectrum we take multiple full field images, each at a different photon energy. Each image is a two dimensional array representing the transmitted photon flux through the sample. The combined data set stacks the individual images along an axis representing photon energy.

CALCULATED SPECTRAL RESOLUTION

A numerical simulation was performed to calculate the expected spectral resolution of our system. We have assumed that the CZP has no aberrations other than the known chromatic aberrations, and that the bending magnet illumination is spatially incoherent. These calculations have been performed with no scanning of the CZP. The CZP-to-sample distance was set at 200 mm for which the energy in focus at the sample plane is 500 eV. The condenser zone plate has 41,000 zones and a 9-mm diameter. There is a 3-mm diameter central stop which obstructs the undiffracted light from reaching the sample.

The convolution of the point spread function of the XM-1 condenser zone plate with the source distribution from the ALS bending magnet yields the field distribution at the sample. The nominal size of the ALS source at the bend magnet is $\sigma = 53 \mu\text{m}$ horizontal and $\sigma = 44 \mu\text{m}$ vertical (2). For a given wavelength, λ , the lens plane field at a point (x, y) from a point source in the source plane with coordinates (ε, η) is (3,4):

$$u(x, y; \varepsilon, \eta) = \frac{1}{i\lambda z_1} \exp\left(\frac{ik}{2z_1}[(x - \varepsilon)^2 + (y - \eta)^2]\right) \quad (1)$$

Where z_1 is the distance from the source to the CZP lens, 17 meters, and the wavenumber, k , is $2\pi/\lambda$. Just past the lens plane, the field of the CZP can be modeled as a simple thin lens:

$$u'(x, y; \varepsilon, \eta) = u(x, y; \varepsilon, \eta) P(x, y) \exp\left(\frac{-ik}{2f}(x^2 + y^2)\right) \quad (2)$$

Where the annular pupil function $P(x, y)$ is 1 between the central obstruction (3 mm diameter) and the lens aperture (9 mm diameter) and is 0 elsewhere. The exponential term is the impulse response of a lens with focal length, f . The field at the image plane (u, v) due to a point source at the source plane is given by the convolution of u' with the point spread function of free space.

$$u_{\text{image}}(u, v; \varepsilon, \eta) = \frac{1}{i\lambda z_2} \iint u'(x, y; \varepsilon, \eta) \exp\left(\frac{ik}{2z_2}[(u - x)^2 + (v - y)^2]\right) dx dy \quad (3)$$

where z_2 , the distance from the lens to the image plane, is 200 mm for this calculation. The convolution with the source can be performed with numerical integration techniques for a series of different photon energies and corresponding different focal lengths from the CZP. The result of these calculations is the illumination at the sample plane for each photon energy. Figure 1 shows the calculated spectral distribution of the illumination near 500 eV on the sample, averaged over areas of $4 \mu\text{m}^2$, $9 \mu\text{m}^2$ and $16 \mu\text{m}^2$. Using ΔE as the FWHM of these distributions, the spectral resolution calculations yield $E/\Delta E = 1400$ within a $4 \mu\text{m}^2$ spot, $E/\Delta E = 900$ within a $9 \mu\text{m}^2$ spot, and $E/\Delta E = 700$ within a $16 \mu\text{m}^2$ spot. Since the best spectral resolution is located at the center of the CZP spot on the sample, the choice of a small area CZP scan sacrifices the field of view for high spectral resolution.

RESULTS

The spectral resolution of XM-1 was measured to be $\Delta\lambda/\lambda = 700$ within the central spot of the condenser. With this spectral resolution, we have observed absorption peaks from the K edges of C, N, O and the L edges of Ca, Ti, V, Cr, Mn, Fe.

The combined capabilities of a high spatial resolution of 36 nm, moderate spectral resolution of $\lambda/\Delta\lambda = 700$, and the ability to image thick, wet samples makes XM-1 a unique tool for many scientific applications. We plan to continue to develop and to actively exploit these features in the future.

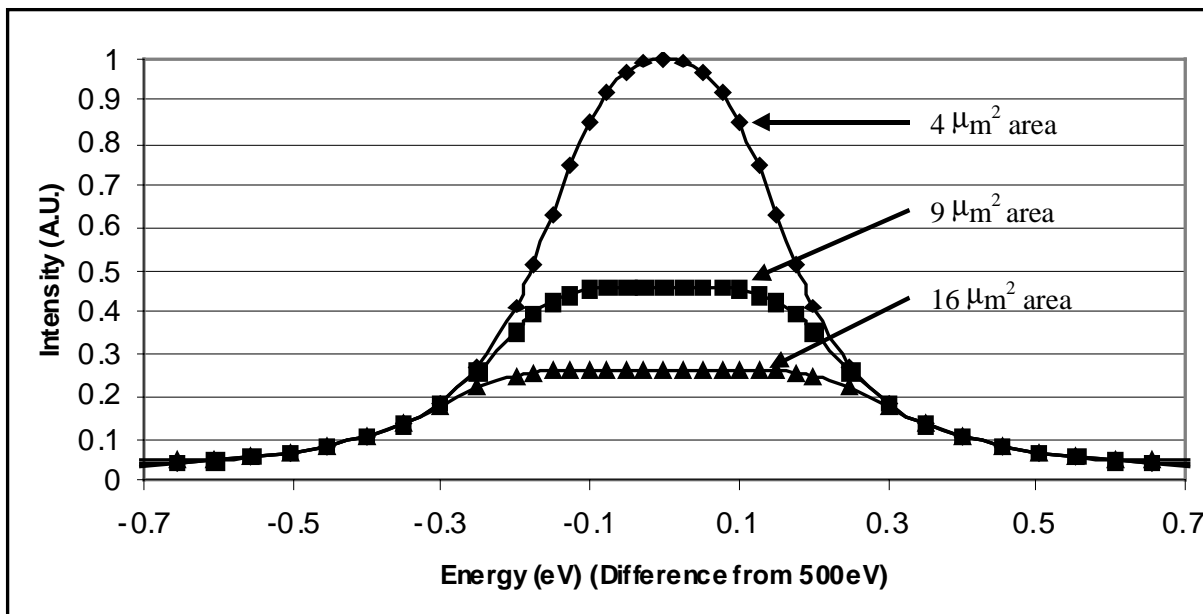


Figure 1. Average intensities at energies near 500 eV for 4 μm^2 , 9 μm^2 , and 16 μm^2 areas.

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